

NEWS RELEASE

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FOR IMMEDIATE RELEASE

ANGSTROM SCIENCES AWARDED PATENT 7,223,322

Pittsburgh, PA, February 4, 2008 - The United States Patent and Trademark Office has issued Patent Number 7,223,322 to Angstrom Sciences, Inc. of Duquesne, Pennsylvania. The patent covers the invention of a moving magnetic/cathode arrangement and method for use in magnetron sputtering thin film deposition.

Planar magnetron sputtering cathodes utilizing rotating magnetics are primarily utilized within cluster tools yielding microelectronic materials requiring the highest order of uniformity. Moving magnetics improve the thin film uniformity on a substrate compared to static magnetron sputtering cathodes. This combined with Angstrom Sciences' profiled magnet technology provides additional utilization of the process target material. The new moving magnetics can be provided to retrofit existing sputtering systems.



Angstrom Sciences is the world leader in magnetron technology used to produce thin films through the sputtering process. Sputtering is used to manufacture advanced products, such as compact disks, energy efficient architectural glass, OLED technology, solar panels, flat panel displays and microelectronic devices. The company has a worldwide business presence, holds several US Patents in magnetron design, and is headquartered in Pittsburgh, PA.

For more information on magnetron sputtering technology, visit Angstrom Sciences at www.angstromsciences.com.